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PATENT  
Dkt. No.: 29273/559

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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

APPLICANTS: Yuko IWABUCHI, et al.  
SERIAL NO. : 10/083,481  
FILED : February 27, 2002  
FOR : METHOD AND AN APPARATUS OF AN INSPECTION SYSTEM  
USING AN ELECTRON BEAM  
GROUP ART : 2881  
EXAMINER : Jack I. Berman

ASSISTANT COMMISSIONER FOR  
PATENTS AND TRADEMARKS  
Washington D.C. 20231

**RESPONSE TO OFFICE ACTION**

Sir:

In response to the Office Action dated June 5, 2002, the due date being extended by the attached Petition for Extension of Time, please amend the above-identified application as follows:

**IN THE CLAIMS:**

Please amend claims 11 and 16 as follows:

11. (Amended) An inspection apparatus using an electron beam according to claim 10, further comprising:

a storage means for storing picture information conveyed by said electrical signal; and a comparator for comparing pictures by using said picture information.

**BEST AVAILABLE COPY**